

other, between the armature coils and itself, practically without generating any magnetic field in an area opposite to the armature unit; and a current driver that moves the magnetic pole unit relatively to the armature unit in a plane parallel to the predetermined plane; and placing the stage unit as the position controller that controls the position of the wafer.

9) added

IN THE ABSTRACT OF THE DISCLOSURE

Please amend the Abstract on page 70 as follows:

By applying a force to cancel a reaction acting on a stator due to driving of a mover to the stator by an electromagnetic interaction generated between reaction canceling magnetic pole units and armature coils, and by having a magnetic pole unit, which constitutes the mover, composed by combining magnets having such magnetization-directions that their magnetic flux are toward the stator and magnets having magnetization-directions crossing the aforementioned magnetization-directions without using yoke material for the mover to be light weight, the vibration of the stator can be prevented even upon the high speed drive of the mover. Therefore, a highly precise positioning control can be performed while moving a placed sample at high speed.

REMARKS

Favorable consideration of this application, as presently amended, is respectfully requested.

The present preliminary amendment is submitted to place the above-identified application in more proper format under United States practice.

By the present preliminary amendment the specification has been amended in the "Disclosure of Invention" section to delete all reference numerals and to correct minor informalities.